

Amendments to the Claims:

This listing of claims will replace all prior versions, and listings, of claims in the application:

Listing of Claims:

1. (Currently amended) ~~A process for treating perfluorides in which decomposition treatment of perfluorides released from a manufacturing plant is carried out comprising:~~

~~using a perfluoride treating apparatus connected to the manufacturing plant; and calculating a cost of treatment of perfluorides according to an amount of perfluorides treated by the perfluoride treating apparatus;~~

~~wherein the perfluoride treating apparatus is provided by a perfluoride treatment undertaker.~~

A process for treating perfluoride released from a manufacturer's plant by a perfluoride treating apparatus owned and provided by an independent separate perfluoride treatment service provider, comprising:

installing the perfluoride treating apparatus owned by the perfluoride treatment service provider at the manufacturer's plant, and connecting the perfluoride treating apparatus to the manufacturer's plant;

using the perfluoride treating apparatus to treat perfluoride released from the manufacturer's plant;

recording information generated by the perfluoride treatment;

calculating a cost and an amount of the perfluoride treatment base on the recorded information;

billing the manufacturer the calculated cost.

2. (Currently amended) ~~A process for treating perfluorides in which decomposition treatment of perfluorides released from a manufacturing plant is carried out comprising:~~

~~using a perfluoride treating apparatus, wherein the apparatus is connected to the manufacturing plant, and~~

~~calculating a cost of treatment of perfluorides according to an amount of perfluorides treated by the perfluoride treating apparatus;~~

~~wherein information of the amount of perfluorides treated are transmitted by a communications network to a server,~~

~~and the server receives the information of an amount of perfluorides treated from a plurality of the manufacturing plants.~~

A process for treating perfluoride released from a manufacturer's plant by a perfluoride treating apparatus owned and provided by an independent separate perfluoride treatment service provider, comprising:

installing the perfluoride treating apparatus owned by the perfluoride treatment service provider at the manufacturer's plant, and connecting the perfluoride treating apparatus to the manufacturer's plant;

using the perfluoride treating apparatus to treat perfluoride released from the manufacturer's plant;

recording information generated by the perfluoride treatment;

calculating a cost and an amount of the perfluoride treatment base on the recorded information, wherein the cost is transmitted to a server of the perfluoride treatment service provider via a network;

billing the manufacturer the calculated cost.

3. (Currently amended) The process according to Claim 1, ~~wherein data of a plurality of specified operations of the perfluoride treating apparatus are the~~ recorded information is transmitted via communication circuits and indicated on a display device.

4. (Currently amended) The process according to Claim 1, wherein the ~~amount of perfluorides treated is determined based on the~~ recorded information includes a flow rate of exhaust gas from the ~~manufacturing~~ manufacturer's plant.

5. (Currently amended) The process according to Claim 1, wherein ~~the amount of perfluorides treated is estimated based the~~ recorded information includes on a flow rate of PFC gas supplied to the ~~manufacturing~~ manufacturer's plant.

6. (Currently amended) The process according to Claim 1, wherein ~~the amount of perfluorides treated is estimated based on the~~ recorded information includes a number of sheets of either blank material supplied to the ~~manufacturing~~ manufacturer's plant or material taken out from the ~~manufacturing~~ manufacturer's plant.

7. (Original) The process according to Claim 6, wherein the blank material is wafer.

8. (Currently amended) The process according to Claim 1, wherein the ~~manufacturing~~ manufacturer's plant is a semiconductor manufacturing plant, and ~~the amount of perfluorides treated is estimated based on the~~ recorded information includes an amount of ~~perfluorides~~ perfluoride required for working wafers in the ~~manufacturing~~ manufacturer's plant.

9. (Currently amended) The process according to Claim 1, wherein the ~~manufacturing~~ manufacturer's plant is either a semiconductor manufacturing plant or a liquid crystal producing plant.

10. (Currently amended) A ~~process system~~ for treating ~~perfluorides~~ perfluoride ~~including an accounting system released from a manufacturer's plant by a perfluoride treating apparatus owned and provided by an independent separate perfluoride treatment service provider,~~ comprising:

means of treating perfluoride connected to the manufacturer's plant;

means for estimating a decomposition treated amount of ~~perfluorides~~ perfluoride contained in exhaust gas from a ~~manufacturing~~ manufacturer's plant based on data of ~~a plurality of operations~~ an operation of the ~~manufacturing~~ manufacturer's plant,

wherein the data of ~~a plurality of operations~~ the operation are transmitted by a communication means to ~~an perfluorides~~ a perfluoride treatment ~~undertaker~~ service provider; and

means for calculating a cost of treatment of the ~~perfluorides~~ perfluoride based on an estimated amount of the ~~perfluorides~~ perfluoride treated; and

means of billing the manufacturer.

11. (Currently amended) The process according to Claim 2, wherein ~~data of a plurality of specified operations of the perfluoride treating apparatus are~~ the recorded information is transmitted via communication circuits and indicated on a display device.

12. (Currently amended) The process according to Claim 2, ~~wherein the amount of perfluorides treated is determined based on~~ the recorded information includes a flow rate of exhaust gas from the ~~manufacturing~~ manufacturer's plant.

13. (Currently amended) The process according to Claim 2, ~~wherein the amount of perfluorides treated is estimated based on~~ the recorded information includes a flow rate of PFC gas supplied to the ~~manufacturing~~ manufacturer's plant.

14. (Currently amended) The process according to Claim 2, wherein ~~the amount of perfluorides treated is estimated based on~~ the recorded information includes a number of sheets of either blank material supplied to the ~~manufacturing~~ manufacturer's plant or material taken out from the ~~manufacturing~~ manufacturer's plant.

15. (Original) The process according to Claim 14, wherein the blank material is wafer.

16. (Currently amended) The process according to Claim 2, wherein the ~~manufacturing~~ manufacturer's plant is a semiconductor manufacturing plant, and ~~the amount of perfluorides treated is estimated based on~~ the recorded information includes an amount of ~~perfluorides~~ perfluoride required for working wafers in the semiconductor manufacturing plant.

17. (Currently amended) The process according to Claim 2, wherein the ~~manufacturing~~ manufacturer's plant is either a semiconductor manufacturing plant or a liquid crystal producing plant.

18. (Currently amended) A process system for treating ~~perfluorides~~ perfluoride released from a manufacturer's plant by a perfluoride treating apparatus owned and provided by an independent separate perfluoride treatment service provider, including an ~~accounting system~~ comprising:

the perfluoride treatment apparatus connected to the manufacturer's plant;

a first computer ~~that estimates~~ configured to estimate a ~~decomposition~~ treated amount of ~~perfluorides~~ perfluoride contained in exhaust gas from a ~~manufacturing the manufacturer's~~ plant based on a data of a ~~plurality of operations~~ an operation of the ~~manufacturing~~ manufacturer's plant, wherein the data of a ~~plurality of operation~~ the operation are transmitted by a communications network to an ~~perfluorides~~ perfluoride treatment ~~undertaker~~ service provider, and;

a ~~processor that calculates~~ second computer configured to calculate a cost of treatment of the ~~perfluorides~~ perfluoride based on an the estimated amount of the ~~perfluorides~~ perfluoride treated.

19. (Currently amended) The process according to claim 18, wherein the first computer is a part of a decomposition treating apparatus.

20. (Currently amended) The process according to claim 18 wherein the ~~processor~~ is second computer includes an information terminal and the communications network in the Internet.

21 . (New) The process according to Claim 1, the recorded information includes data of an operation of the perfluoride treating apparatus.